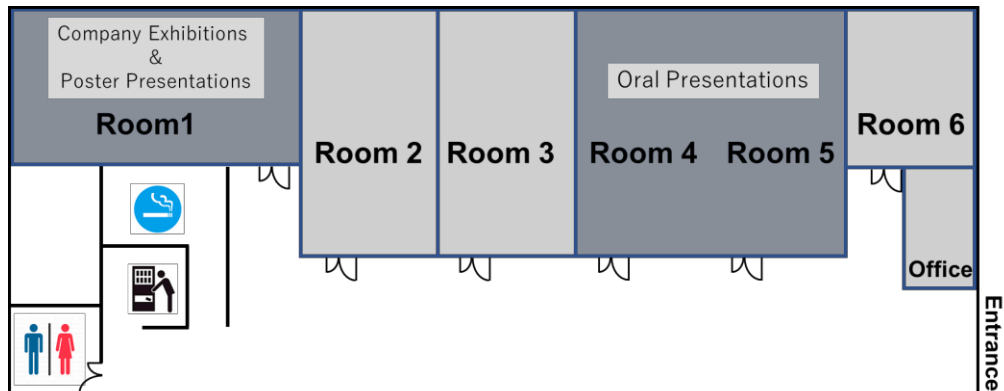
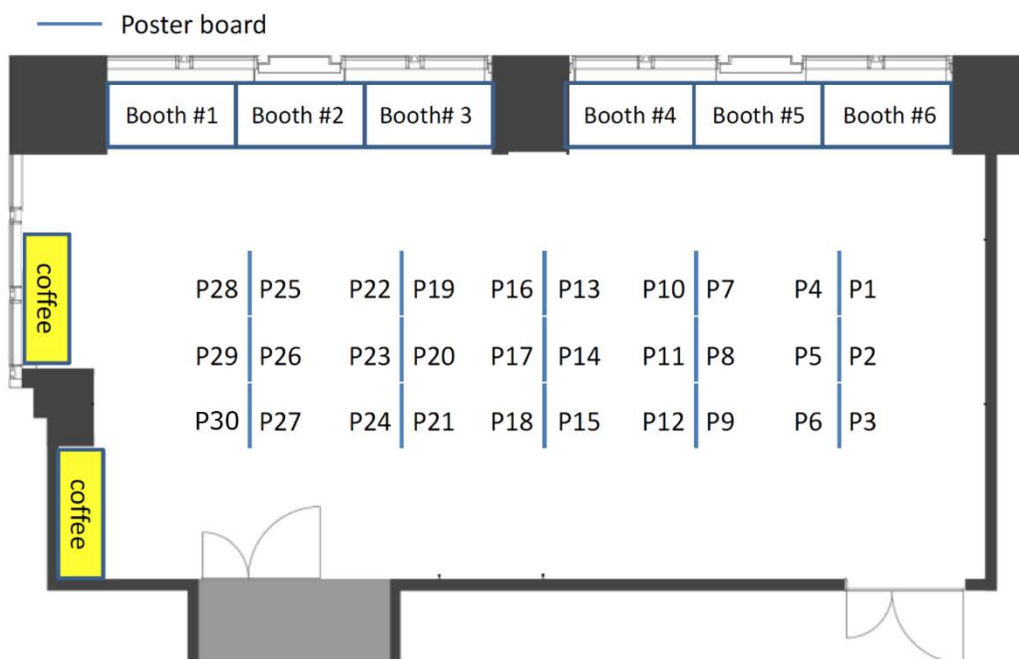


Venue: TRUST CITY CONFERENCE Sendai (Trust City Tower 5F)

Floor Map



Exhibition booths and Posters in Room 1



Company Exhibitions

| | |
|-----------------|--|
| Booth #1 | Carl Zeiss X-ray Microscopy, Inc. |
| Booth #2 | Hamamatsu Photonics K.K. |
| Booth #3 | JTEC Corporation |
| Booth #4 | microworks GmbH |
| Booth #5 | RIGAKU Corporation |
| Booth #6 | TDC Corporation |

Poster Presentations

- P1** **Kiyoshi Hayashida** (Osaka University, Japan)
Scalable mission plans from sub-arcsecond to micro-arcsecond X-ray imaging with multi image X-ray interferometer method (MIXIM)
- P2** **Shunji Kitamoto** (Rikkyo University, Japan)
Sub-arcsec imaging with a normal incident EUV telescope
- P3** **Nozomi Nakaniwa** (Rikkyo University, Japan)
Development of X-ray mirror using hot plastic deformation process
- P4** **Chisato Oue** (Ehime University, Japan)
Development of the method of shaping the mirror surface on carbon fiber reinforced plastic (CFRP) substrates
- P5** **Yusuke Takehara** (Nagoya University, Japan)
Developments of space electroformed-nickel optics and atomically-thin graphene films linking space and ground-based technologies
- P6** **Wenbing Yun** (Sigray Inc., USA)
Novel, high efficiency x-ray optics for synchrotron and laboratory equipments
- P7** **Hirokatsu Yumoto** (JASRI/SPring-8, Japan)
Alignment mechanism for nano-focusing with ellipsoidal mirror
- P8** **Shunya Yokomae** (The University of Tokyo, Japan)
Construction of a precision surface machining system for axisymmetric soft X-ray mirrors
- P9** **Gota Yamaguchi** (The University of Tokyo, Japan)
Focusing soft X-rays by Cu-electroformed ellipsoidal mirror

- P10** Takashi Imazono (QST, Japan)
Design of a high-resolution flat-field grating spectrometer for tender X-ray emission spectroscopy
- P11** Masato Koike (QST, Japan)
Design of valid line spacing holographic grating with high groove density and multilayered laminar-type grooves for flat field spectrometer optimized for 200–900 eV region
- P12** Tadashi Hatano (Tohoku University, Japan)
LaF₃- and La/C-coated high efficiency laminar-type diffraction gratings for B K-emission spectroscopy
- P13** Tetsuo Harada (University of Hyogo, Japan)
Development of high-quantum-efficiency (>90%) backside-illuminated CMOS sensor in soft X-ray region with high exposure durability
- P14** Takeo Ejima (Tohoku University, Japan)
Luminescence properties of scintillators in the energy region from 300 eV to 1.3 keV
- P15** Satoshi Ohdachi (NIFS, Japan)
Detection of the magnetic field structure using 2D soft X-ray imaging of the magnetically confined fusion plasmas
- P16** Takuji Ohigashi (IMS, Japan)
Low energy optics for a scanning X-ray transmission microscope at UVSOR-III
- P17** Takuo Ohkochi (JASRI/SPring-8, Japan)
Present status of development and utilization of soft X-ray photoemission electron microscopes in SPring-8
- P18** Masaya Torigata (Tokai University, Japan)
Imaging of oxidative damage in human hair exposed to solar-UV radiation by X-ray spectromicroscopy at the S-K absorption edge
- P19** Yasushi Kagoshima (University of Hyogo, Japan)
Practical designing of inverse-phase composite zone plate for deeper depth of focus
- P20** Yasushi Kagoshima (University of Hyogo, Japan)
Measurement of horizontal beam emittance of undulator radiation by tandem-double-slit optical system

- P21** Akihisa Takeuchi (JASRI/SPring-8, Japan)
Nondestructive multiscale X-ray tomography for nanometer scale 3D/4D imaging for bulky object
- P22** Yoshio Suzuki (The University of Tokyo, Japan)
Hard x-ray schlieren microscopy and its application to tomography
- P23** Atsushi Momose (Tohoku University, Japan)
Development of grating-based super-resolution X-ray phase imaging
- P24** Pouria Zangi (KIT, Germany)
Fabrication of gratings for super-resolution X-ray phase imaging using deep X-ray lithography (DXRL)
- P25** Norio Watanabe (University Tsukuba, Japan)
X-ray differential phase imaging using foucault knife-edge and diffuser plate
- P26** Yanlin Wu (Tohoku University, Japan)
High-speed grating interferometer-based X-ray vector radiography
- P27** Yanlin Wu (Tohoku University, Japan)
High-resolution of Talbot interferometry type full-field X-ray microscopy for bone specimens
- P28** Takaya Higashino (Osaka University, Japan)
Observation of structural changes in melting process of Pb-Sn eutectic alloy particles by in situ X-ray ptychography
- P29** Nozomu Ishiguro (Tohoku University, Japan)
Ptychographic imaging using hard X-ray multibeam
- P30** Konstantins Jefimovs (Paul Scherrer Institute, Switzerland)
Displacement Talbot lithography for X-ray Talbot imaging on 8-inch wafer scale